## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): NISHIO, et al.

Application No.: 10/583,348

Filed: June 19, 2006

For: Method for Removing Deposit from Substrate and Method

FOR DRYING SUBSTRATE, AS WELL AS APPARATUS FOR REMOVING

DEPOSIT FROM SUBSTRATE AND APPARATUS FOR DRYING

SUBSTRATE USING THESE METHODS

## **RESPONSE TO MISSING PARTS**

Mail Stop Missing Parts
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

April 5, 2007

Sir:

In response to the Office Letter dated February 5, 2007, in connection with the above-identified application, attached hereto is an executed Declaration for Patent Application in compliance with 37 CFR 1.63.

The fee of \$130.00 required to satisfy the requirements set forth in 37 CFR 1.16(f) is being submitted electronically at the time of filing this response.

Please charge any shortages in the fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account No. 01-2135 (Docket No. 1343.46195X00) and please credit any excess fees to such deposit account.

Respectfully submitted,

/Alan E. Schiavelli/

Alan E. Schiavelli Registration No. 32,087

AES/ayy (703) 312-6600